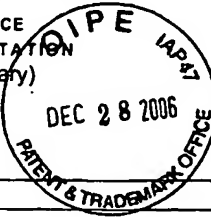


FORM HDP-1449 (Based on Form PTO-1449)  PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)  Sheet 1 of 1	ATTORNEY DOCKET No.	SERIAL No.
	2421-000030/US	10/726,638
	APPLICANT	
	Ja-Hum KU et al.	
	FILING DATE	GROUP
	December 4, 2003	2812



U.S. PATENT DOCUMENTS						
Ref. Desig.	Examiner's Initials	Document Number	Date	Name	Class/ Subclass	(If appropriate) Filing Date
11B	11B	US 6,531,396	03-11-2003	Dongzhi CHI et al.		
11B	11B	US 6,376,342	04-23-2002	Hong-Huei TSENG		
11B	11B	US 6,388,327	05-14-2002	Kenneth J. GIEWONT et al.		
11B	11B	US 4,141,022	02-20-1979	Hans J. SIGG et al.		

FOREIGN PATENT DOCUMENTS							
Ref. Desig.	Examiner's Initials	Document Number	Date	Country	Class/ Subclass	Translation Yes	No
11B	11B	WO 02/065524	08-22-2002	WIPO			
11B	11B	JP 2002/124487	04-26-2002	Japan		Abstract	
11B	11B	JP 2003/168652	06-13-2003	Japan		Abstract	
11B	11B	EP 0 501 561	09-02-1992	Europe			

OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, etc.)		
Ref. Desig.	Examiner's Initials	
11A	11B	Sun M C et al., "Thermally Robust Ta-Doped Ni Salicide Process Promising for sub-50nm CMOSFETs", <i>Digest of Technical Papers</i> , New York, NY, June 10, 2003, pages 81-82.

Examiner:	Date Considered: 1/21/07
-----------	--------------------------

EXAMINER: Please initial if citation considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.